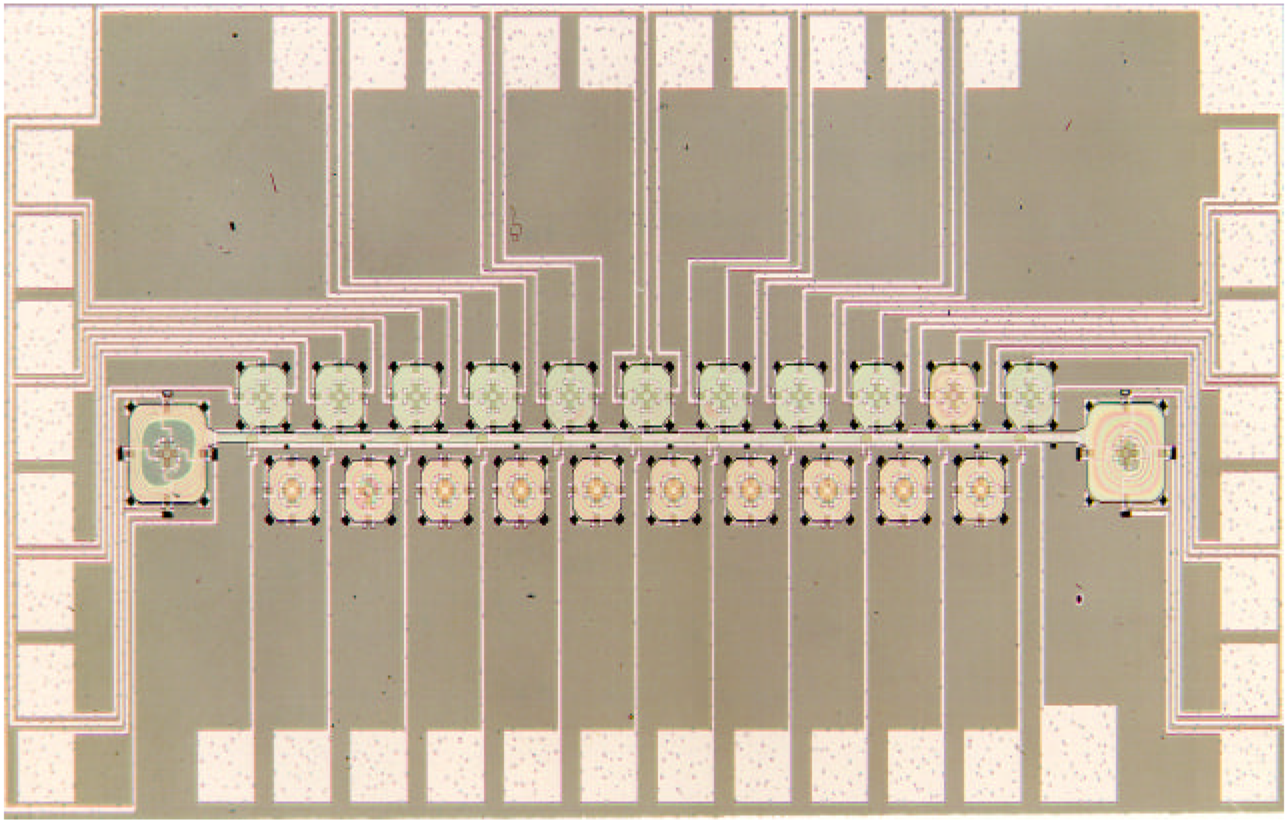
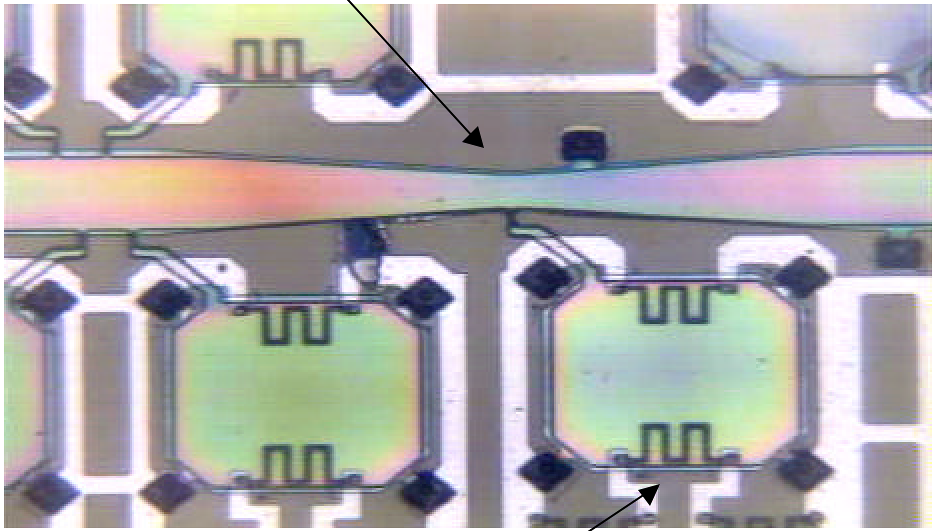
Miniaturized Pipe Flow



Microchannel with multiple pressure sensors
channel size 1 by 5 μm

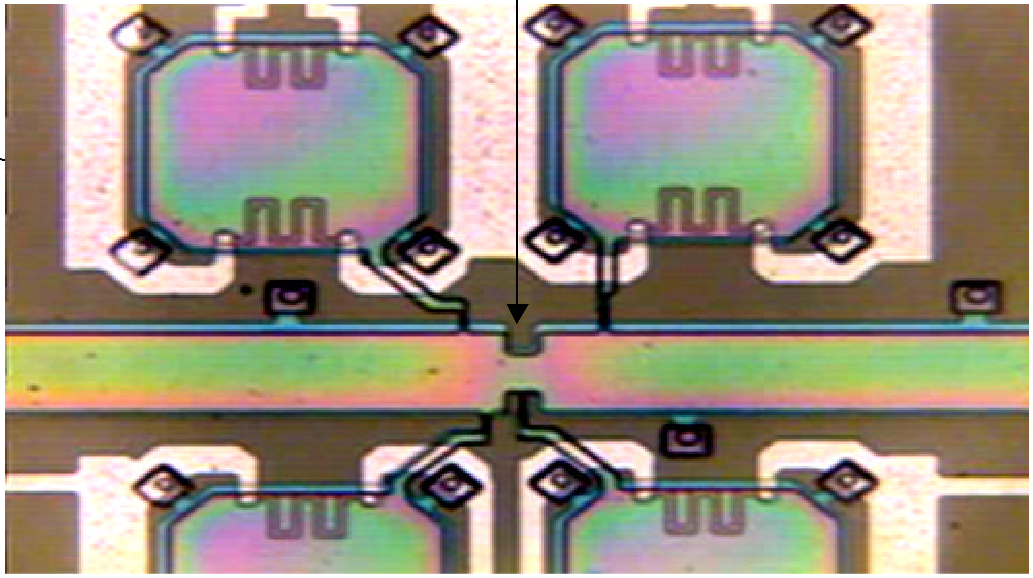
Micro Venturi & Orifice Tubes

Throat 1 by 20 µm



Pressure sensors

Orifice restriction
1 by 20 µm



MEMS (MicroElectroMechanical Systems)

MEMS Clearing House: A Tutorial

MEMS Sandia Laboratory

DARPA MEMS Program